



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Takatoshi Tsujimura et al.
Serial No.: 10/693,244
Filed: October 24, 2003
For: Forming a Thin Film Structure

§ Group Art Unit: 1762
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§ Examiner: David P. Turocy
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§ Atty. Dkt. No.: CMO.0012US
§ (P030096ATZLUS)

Mail Stop Amendment

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Dear Sir:

Applicant submits the references listed on the attached form PTO 1449 together with any required copies of such references.

Please apply any additional charges or credits to Deposit Account No. 20-1504 (CMO.0012US).

Respectfully submitted,

Date:

Sept 7, 2007

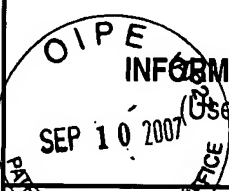
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I hereby certify under 37 CFR 1.8(a) that this correspondence is being deposited with the United States Postal Service as **first class mail** with sufficient postage on the date indicated above and is addressed to the Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

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 <p style="text-align: center;">INFORMATION DISCLOSURE CITATION</p> <p style="text-align: center;">(Use several sheets if necessary)</p>	ATTY DOCKET NO. CMO.0012US (P030096ATZLUS)	SERIAL NO. 10/693,244
	APPLICANT(S): Takatoshi Tsujimura et al.	
	FILING DATE: October 24, 2003	GROUP ART UNIT: 1762

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
A.						
B.						
C.						
D.						
E.						

U.S. PATENT APPLICATION PUBLICATIONS

F.						
G.						
H.						
I.						
J.						

FOREIGN PATENT DOCUMENTS

DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
					YES	NO
K.						
L.						
M.						
N.						
O.						

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

P.	A.P. Constant et al., "Thin Film Transistors Based on Microcrystalline Silicon on Polyimide Substrates," Materials Research Society Symp. Proc., Vol. 557, pp. 683-688, (1999).
Q.	
R.	
S.	
T.	
U.	
V.	

EXAMINER	DATE CONSIDERED
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.